



Wafer characterization tests MAIA BEE project

Overview
Wafer characterization
Sensor test
In situ debug and maintenance DAQ

LPC LAL LLR

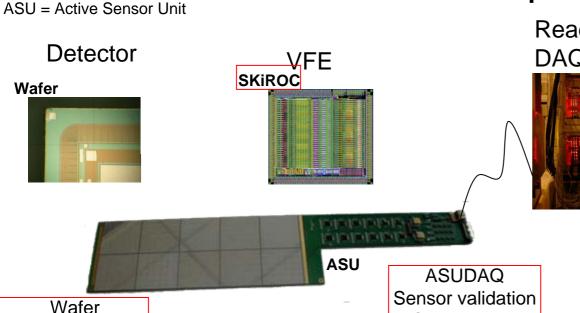






Instrumental chain ongoing work at LPC from Wafer to data acquisition





Read-out DAQ

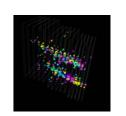


first developments of a generic design

Test bench



Analysis Software



econstruction SW

ISDDAQ Debug, Monitoring Maintainance

ISDDAQ architecture issue

On beam integration

Architecture level R&D

Wafer test bench being set up

- 3x3 Test wafers specifications
- Probe tips test apparatus
- Silicon simulation tools

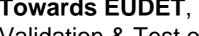
Towards EUDET.

Validation & Test of the whole chain

Cosmic tests

ASUDAQ prototype

- R&D test tools for sensor and electronics
- Validation, debugging and maintenance on beam





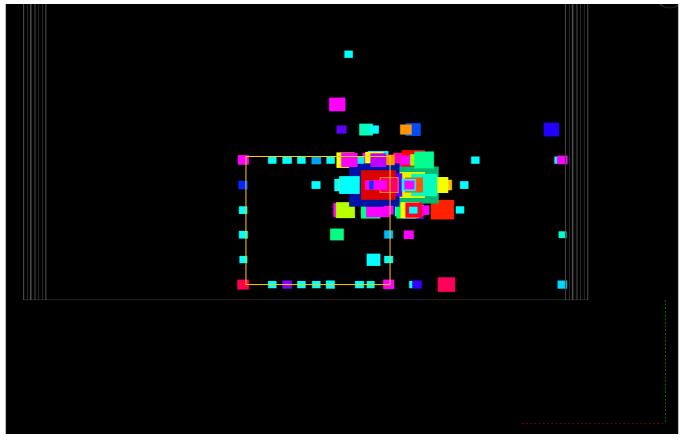
Crosstalk studies

Design validation

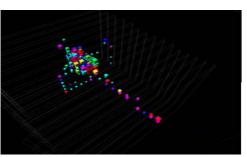


Wafer

Unexpected behavior seen during test beam : SQUARE events ! Unmatched pattern according to physics models... Has to be understood and solved

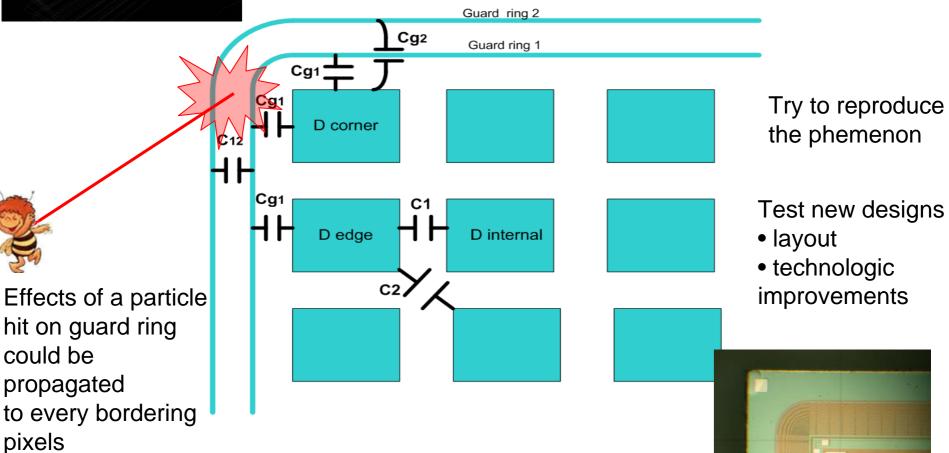






Wafer

Understand Square events origins Crosstalk studies according to design options



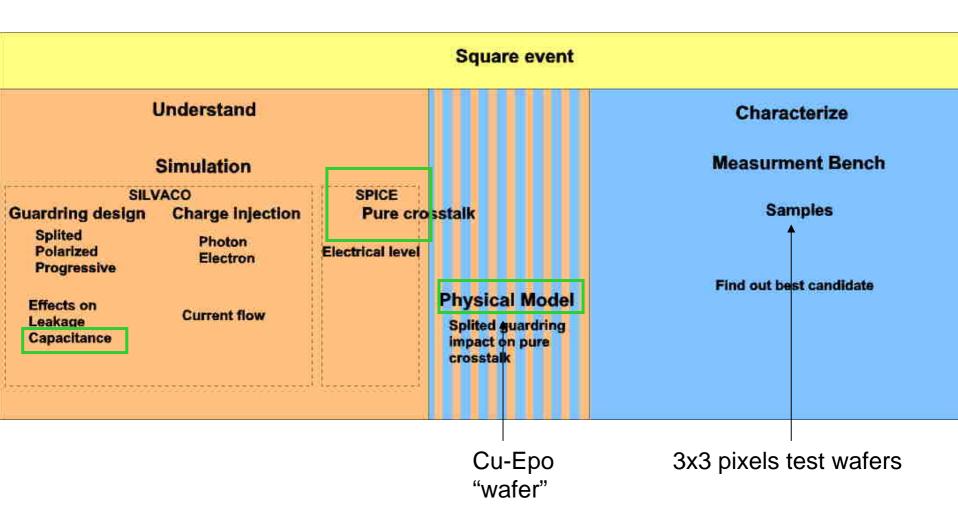
4

Various 3x3 test wafer to be produced by OnSemi

As result, select the best design technique...

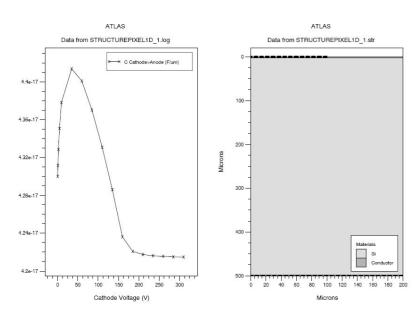


Wafers: Method





SILVACO SIMULATIONS



C(V) between pixel and common bias and C(V,f,a,b,c,d...)

First step to verify capacitance values between pixels, guardrings, substrate

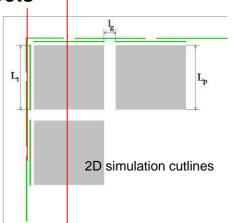
Then back annotate to SPICE simulation

Simulated Cap. Values are within a 20% range from expected values calculated with first order formula

3D simulation are ongoing to take into account border effects

Second step to simulate ionization effects (electron or photon) or SEE/SEU events

Third step (following months) to evaluate design parameters impact on C and explore new designs of guardrings from crosstalk point of view



Segmented guardring technique may prevent Xtalk by a factor 3

diaphonie pixel – 3x3 matrix

Cgb = 4 pF Cgg=24pF Cpg = 1 pF



SPICE

	Plain guardring						
5.6			5.6		5.6		
		1	100	1			
5.6		0.3		0.3	5.6		
		0.5	0.3	0.5			
5.6			5.6		5.6		

Guardring	non segme	enté, Signal	l at G1	
		100		
	20	5.6	20	
	5.6	-	5.6	
	20	5.6	20	

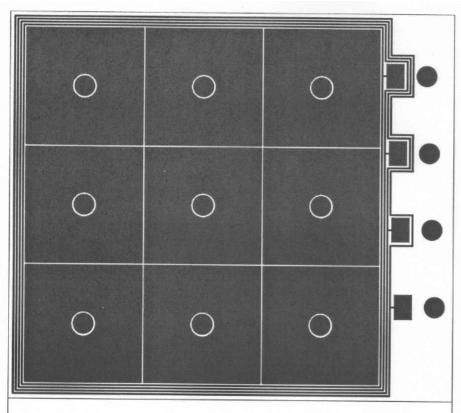
Segmented guardring 160 fF				
2		42		2
	0.3	100	0.3	
2	0.1	-	0.1	2
	0.15	0.08	0.15	
2		2		2

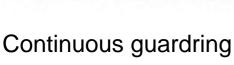
	g 1 segment =160 fF	té, Signal at G1_2 segment,		
6		100		6
	1	5.6	1	
4	0.2	-	0.2	4
	0.4	0.2	0.4	
4		4		4

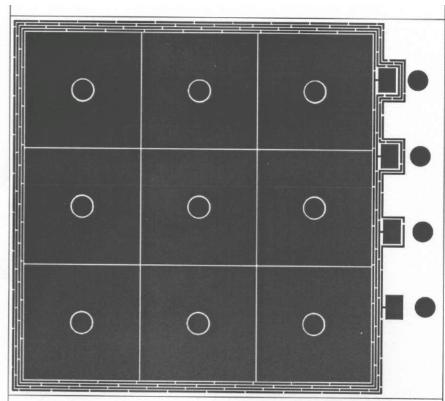


Physical Model: Cu-Epoxy

- Study pure crosstalk effects (various configurations)
- Measurement method validation
- Test bench calibration





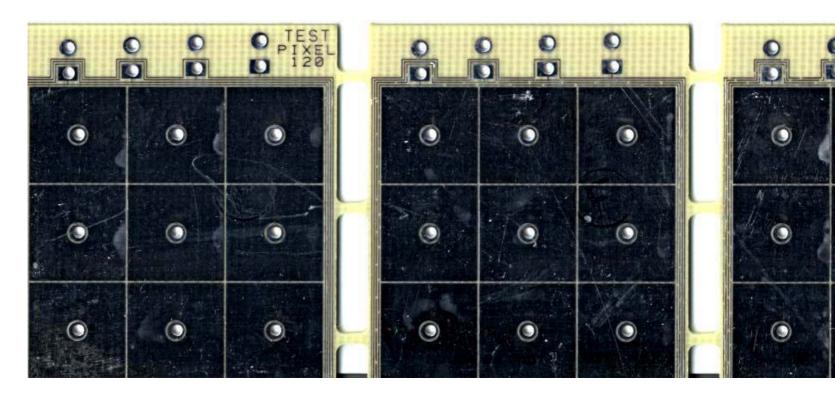


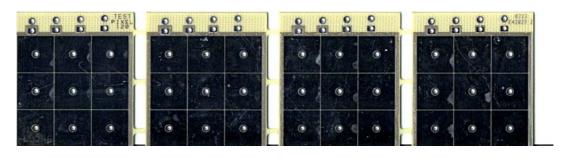
Splited guardring

- •4 @ 1 cm
- •4 @ 3 mm
- •2 @ 1 cm + 2 unsplited



Physical Model: Cu-Epoxy





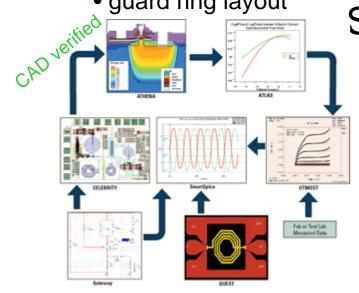
Simulation

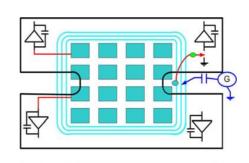
capacitive coupling

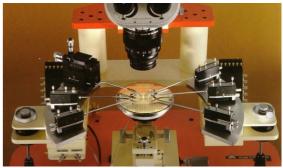
guard ring layout

Wafer Setup and tools









PCB for test electronics

Supporting PCB

Wafer

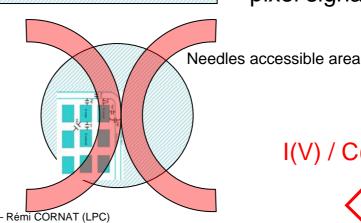
XYZ table

Characterization

- Charge injection
- pixel signal analysis

Test bench

- pulse generator
- micropositioner & probes
- shaper + scope



I(V) / C(V

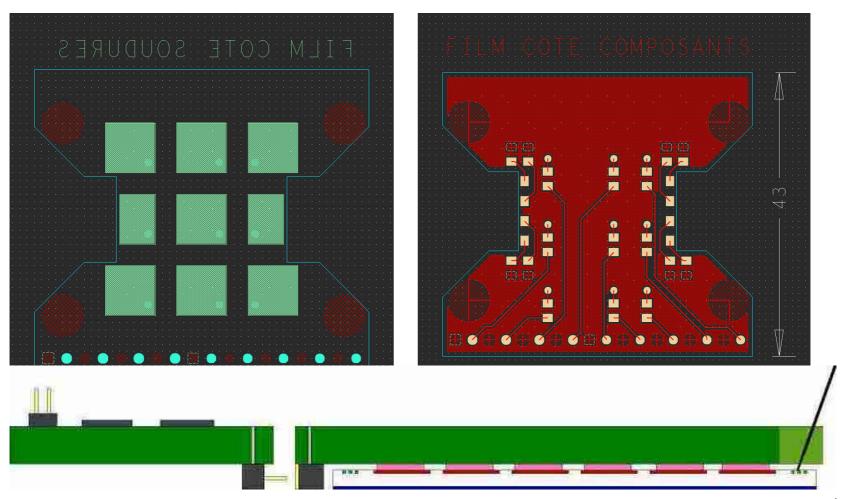
10

CALICE - 12/07/07 - Rémi CORNAT (LPC)



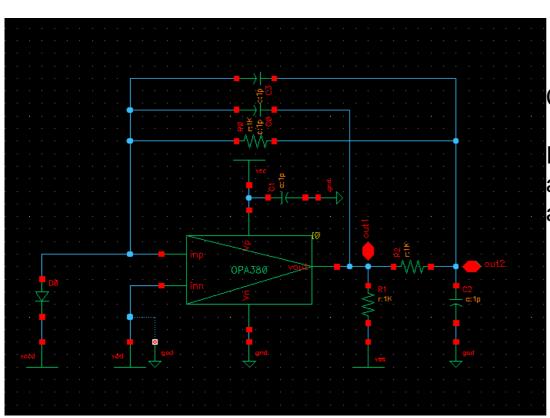
PCB to glue 3x3 test wafers

Sent to fab. Last week





Instrumentation board



Sent to fab. Last week

Compatible with wafer gluing PCB

Includes 3 OPA for signal shaping and transimpedance adaptation to a scope

Nice picture of the board here

OPA380 or OPA657





= done or good results

Wafer actions

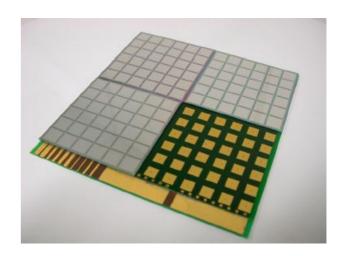


Simulation

- Software know-how & test case (first try on 10th of april)
- Simulate: depletion area between segments, polarization effects, photon or electron effects, capacitance extraction, multiple pixels and guardring, 3D
- Comparison with test beam data (may validate "pure crosstalk" hypothesis)

Physical Model

- Layout
- Simulations (Spectraa, spice)
- Bench tests during July
- Measurement bench
 - Assembly (black box, Keithley,...)
 - Test board design
 - Connector
 - Charge injector
 - Shaper
 - 3x3 matrix specifications
 - · Back from fab. on oct/nov
 - Measurements will follow
- Interaction with manufacturer
 - Layout options
 - Common wafer floorplan



Part II



MAIA BEE

M aintenance

A pparatus

I ncluding (data)

A cquisition (on)

B eam (for)

E UDET

E CAL



{ASUDAQ, ISDDAQ} = MAIA BEE

ASUDAQ = ASU DAQ

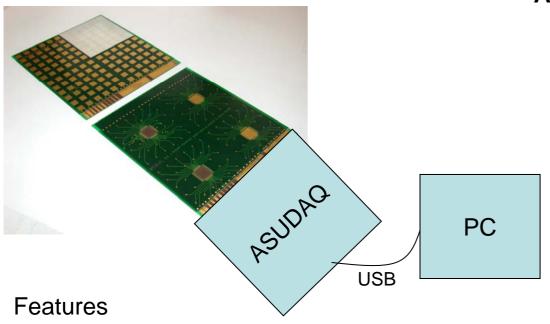
ASUDAQ = In Situ Debug DAQ (of one SLAB)



ASUDAQ

Cosmic test of ASU

Active Sensor Unit



Cosmic test bench for ASU characterization.

First R&D step towards EUDET production tests

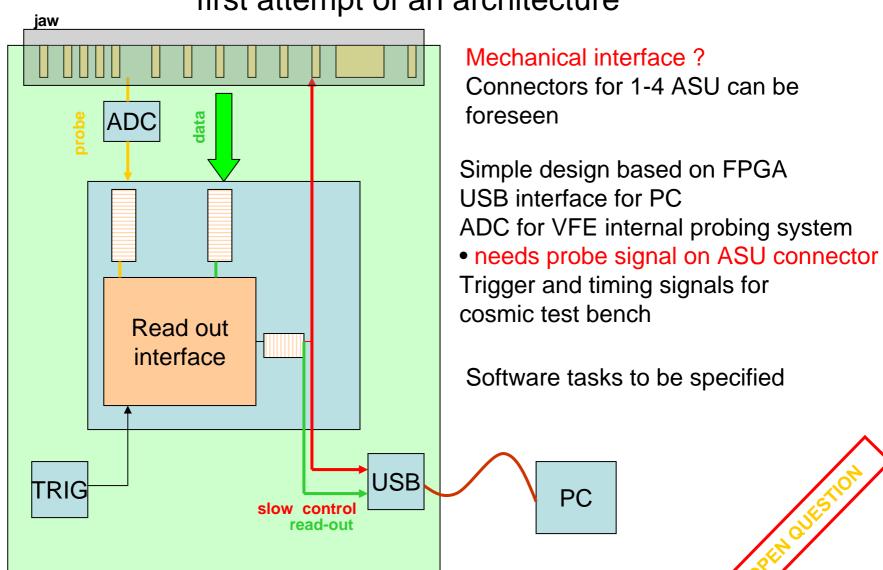
- full **slow control** including internal probing system control
- access to analog test points (embedded ADC)
- read out of 4 SKiROC through USB & PC
- cosmic bench environment support (triggers)
- mechanical jaw providing damageless contacts to ASU

A board is being designed : schematic mostly done



ASUDAQ

first attempt of an architecture





ASU/SLAB connector I/O LPC 22/06/07

				_
CAT	NAME			
HV				
POWER	GND		1	
	3.3V		1	
BIAS			0	
REFERENC	E		0	
ccc	clkp 40MHz	1 LVDS	0	
	clkn 40MHz			
	Reset	1 OC	oc	
	power_on_xxxx	5 LVTTL	0	new 22/06
	testin	analogue	0	new 22/06
sc	clk_sc	1 LVTTL	0	
	rstb sc	1 LVTTL	0	
	sroutscbuf	1 LVTTL	ı	
	srin_sc	1 LVTTL	0	
PROBE	analogue_probe	analogue	Ain	
	digital_probe	1 LVTTL	I	
READOUT	clkp_5MHz / 1 MHz	1 LVDS	0	
	clkn_5MHz / 1 MHz			
	StartAcq	1 LVTTL	0	
	ValEvtp	1 LVDS	0	
	ValEvtn			
	RazChnp	1 LVDS	0	
	RazChnn			
	StartReadOut	1 LVTTL	0	
	EndReadOut	1 LVTTL	ĭ	
	TransmitOn	1 LVTTL	i	
	Dout (out0)	1 LVTTL	i	
	RamFull	100	oc	
	TriggerExt	1 LVTTL	0	
		1 LVTTL	ĭ	
	TriggerOut	TEVITE	'	

ASU connector

To be discussed

More I/O added to current board to follow SKiROC developments



InSituDebugDAQ concept

On beam simplified DAQ devoted to monitor and debug a few SLABs

- chip radiation tolerance
- accurate diagnostic of unexpected behavior
- monitoring (internal probes)
- maintenance

Can run alone, eventually with no beam

 compatible with machine interface or specific trigger and timing

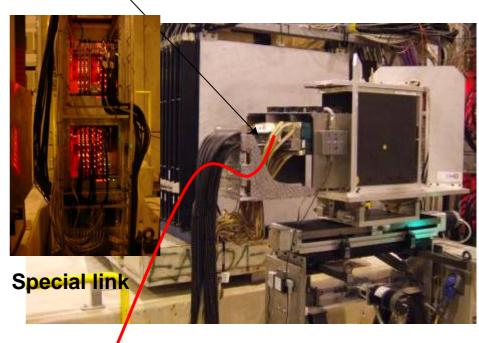
Dedicated Software aimed to ease

debugging

Simultaneous DAQ operations allowed

Machine
Interface
Or
Stand alone
CCC

Standard DAQ

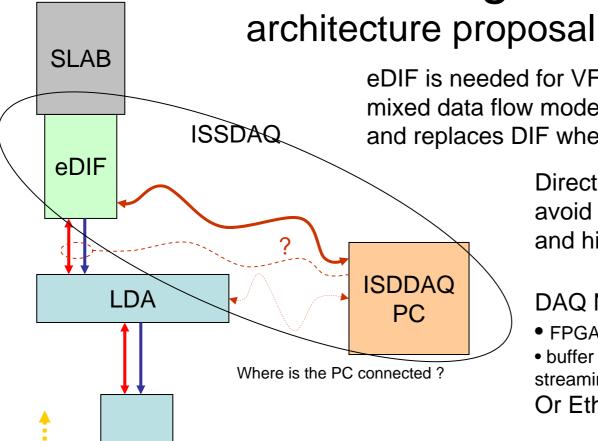


DebugDAQ Dedicated PC

Needs DIF (already connected to SLAB)



InSituDebugDAQ



ODR

TRIG

eDIF is needed for VFE probes and mixed data flow mode (probe+DAQ) and replaces DIF when debugging

> Direct connection to LDA would avoid risky cabling operations and highest flexibility

DAQ NI PCI-7811R?

- FPGA based, 160 I/O to PCI
- buffer flush mode (continuous streaming to PC)

Or Ethernet

Software tools

Then it needs (e)xtended LDA... (CCC multiplexing) or custom interface board (serial LVDS to NI DAQ)

Light LDA for early devlopments



ASU DAQ vs DIF (idea)

Hard/firm/software developments for ASUDAQ & ISDDAQ are Very similar as for DIF

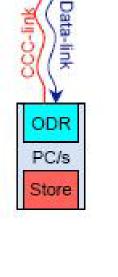
ISDDAQ is a DIF with extended features and direct read-out

DIF is a light ASUDAQ, ASUDAQ is a DIF with extended features

- slow control of internal probes
- ADC for probe output (will be integrated into VFE ?)
- probe data read-out (additional or separate flow)
- dedicated software modules

CCC additionnal signals for users defined trigger (cosmic, no beam, ...)
Alternative Slow control access
Mechanical interface to ASU (ASUDAQ)



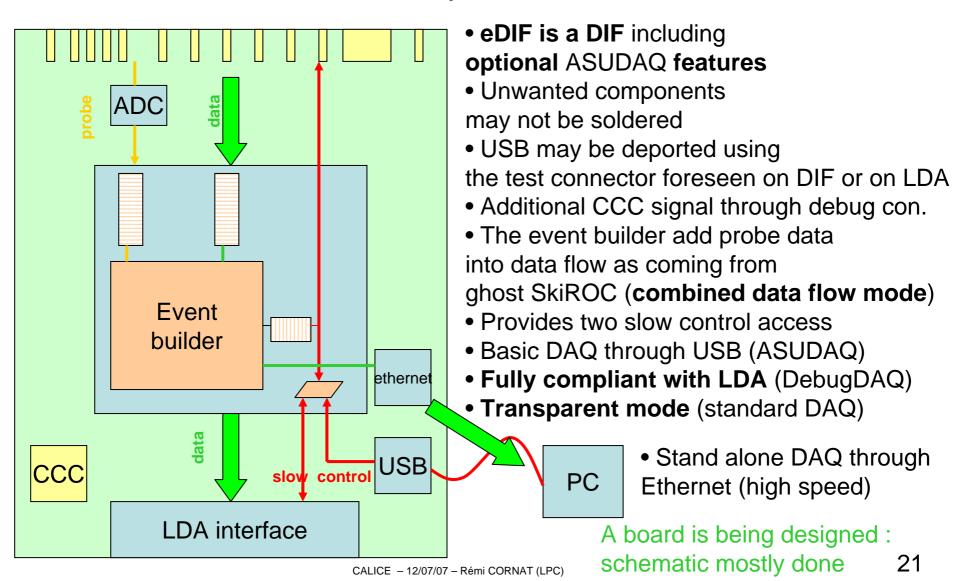


LDA



eDIF proposal

first attempt architecture





Conclusion

ASUDAQ and ISDDAQ need analogue signals of internal probing system to be connected to DIF

- eDIF concept
- architecture choice
- Combined data flow mode

Wafer test bench being set up

- PCB specifications
- Keithley choice
- Shaper
- SILVACO simulation tools



ASUDAQ

- first developments on prototyping board
- ASU connector issue

ISDDAQ architecture issue

- Internal probes
- Simultaneous DAQ
- Flexibility

Common "all in one" prototype is being designed

- generic interfaces
- use of additional adapter board to connect to ASU, SLAB, etc...